

Notice of References Cited	Application/Control No. 10/823,298	Applicant(s)/Patent Under Reexamination REN, LIPING	
	Examiner Marcos D. Pizarro-Crespo	Art Unit 2814	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	C	US-			
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	M	US-			

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Ghandhi; VLSI fabrication principles: silicon and gallium arsenide; 1994; John Wiley & Sons, Inc., New York; 2nd edition; pp.258-259.
	V	Van Zant; Microchip fabrication: a practical guide to semiconductor processing; 2000; Mc-Graw Hill, New York; 4th edition; pp.382,511
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.